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STATEMENT BY APPLICANT**

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Complete If Known

Application Number	10/821,010		
Filing Date	April 8, 2004		
First Named Inventor	Xuming Xiong		
Art Unit	1775 1793		
Examiner Name	Unassigned		
Sheet	1	of	1
		Attorney Docket Number	1014-SP215-US

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	A	Y. Iijima, et al., "In-Plane Aligned YBa ₂ Cu ₃ O _{7-x} Thin Films Deposited on Polycrystalline Metallic Substrates", Appl. Phys. Letters, Vol. 60, pp. 769-771, 1992.	
	B	X. Wu, et al., "Properties of YBa ₂ Cu ₃ O _{7-s} Thick Films on Flexible Buffered Metallic Substrates", Appl. Phys. Letters, Vol. 67, No. 16, pp. 2397-2399, 1995.	
	C	H. Freyhardt, et al., "YBaCuO Thick Films on Planar and Curved Technical Substrates", Vol. 7, No. 2, pp. 1426-1431, 1997.	
	D	R. Huehne, et al., "Growth of Biaxial Textured MgO-Layers by Ion-Beam Assisted Pulsed Laser Deposition", Crystal Res. Technology, Vol. 35, No. 4, pp. 419-425, 2000.	
	E	L. Dong, et al., "Texture Development Mechanisms in Ion Beam Assisted Deposition", Journal of Applied Physics, Vol. 84, No. 9, pp. 5261-5269, 1998.	
	F	J. Groves, et al., "Recent Progress in Continuously Processes IBAD MgO Template Meters for HTS Applications, Physica C 382, pp. 43-47, 2002.	
	G	ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /K.M.V./	
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	I		
	J		

Examiner Signature	/Kallambella Vijayakumar/	Date Considered	10/01/2008
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

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